SEMIPROBE[®]

SUCCESSFUL APPLICATION: DEVICE CHARACTERIZATION - 1121



Specific Requirements:

A company wanted a modular, flexible, and small footprint probe system that could easily be moved to and placed on workbenches in the lab next to the test instrumentation. The probe system would primarily be used to test packaged parts, die, and small wafers and interfaced to a variety of test instrumentation.

SemiProbe Solution:

- LA-100 manual 100 mm probe system:
 - Manual wafer stage with coarse and fine X, Y, Z, and theta movement
 - 100 mm wafer chuck (non-thermal) with concentric vacuum rings to hold die, partial wafers, and whole wafers up to 100 mm
 - Platen with magnetic skin
 - Vibration isolation table with casters and leveling feet
 - Removable front-wedge and platen lift
- Post with microscope movement coaxial and linear 100 mm X and Y travel
- Stereo Zoom Optics CCTV System color camera
- Four manual manipulators MA-8005 with coaxial and triaxial probe arms